

## **MCN VENDOR WEEK PROGRAM: FEB 1 – 3 2012**

*A Showcase of Nanotechnology: Present & Future*

### **Day 1 – February 1, 2012**

<b>TIME</b>	<b>BOARDROOM</b>	<b>BIOLAB</b>	<b>CLEANROOM</b>
10:00 AM – 11:00 AM	IntlVac Reactive Sputter & Electron Beam Deposition Capabilities & Applications Dino Deligiannis (IntlVac)	N/A	N/A
11:00 AM – 12:00 PM	E-Beam Lithography-Simulation & Correction of Proximity and Process Effects Nezih Unal (GenISys)	N/A	N/A
12:00 PM – 1:00 PM	LUNCH/Welcome by MCN Managing Director & Science Director	N/A	N/A
1:00 PM – 1:30 PM	Objet 3D Printing Capabilities & Applications Travis Hardy (3D Systems Asia-Pacific)	N/A	N/A
1:30 PM – 2:30 PM	UV/VIS/NIR Spectrophotometry Capabilities Paul Barrett (ATA Scientific)	N/A	N/A
2:30 PM – 3:00 PM	AFTERNOON TEA	N/A	N/A
3:00 PM – 4:00 PM	What's new in Nikon Laser Microscopy Andrew Marshall (Coherent Scientific)	N/A	N/A
4:00 PM – 5:00 PM	N/A	Nikon Optical Microscopes/UV Spectrophotometer/Objet 3D Printer Demos	N/A

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**Day 2 – February 2, 2012**

<b>TIME</b>	<b>BOARDROOM</b>	<b>BIOLAB</b>	<b>CLEANROOM</b>
10:00 AM – 11:00 AM	Scanning Force Microscopy in Biophysics & Materials Science Christian Loebbe (Scitech)	N/A	Veeco AFM Demo Session 1 (Class 10,000)
11:00 AM – 12:00 PM	The Mechanical Characterization of Nanostructured Biomaterials James Best (University of Melbourne)	N/A	Veeco AFM Demo Session 1 (Class 10,000)
12:00 PM – 1:00 PM	LUNCH	N/A	N/A
1:00 PM – 1:30 PM	EVG Photolithography/NIL/Hot Embossing Techniques & Capabilities Thomas Glinser (EVG)	JPK Biological AFM Demo Session 1	N/A
1:30 PM – 2:00 PM	EVG Photolithography/NIL/Hot Embossing Applications Frank Huysmans (EVG)	JPK Biological AFM Demo Session 1	N/A
2:00 PM – 2:30 PM	Oxford Reactive Ion Etching Techniques & Capabilities Robert Gunn (Oxford)	JPK Biological AFM Demo Session 2	EVG Mask Aligner/Hot Embosser Workshop 1 (Class 100)
2:30 PM – 3:00 PM	Oxford Reactive Ion Etching Process Development Robert Gunn (Oxford)	JPK Biological AFM Demo Session 2	EVG Mask Aligner/Hot Embosser Workshop 1 (Class 100)
3:00 PM – 3:15 PM	AFTERNOON TEA	N/A	N/A
3:15 PM – 4:00 PM	Current trends in Atomic Force Microscopy Ang Li (Bruker)	N/A	N/A
4:00 PM – 5:00 PM	History of E-Beam Lithography Mike Butler (Vistec)	N/A	N/A
5:00 PM – 6:30 PM	Drinks & Nibbles (Kitchen/Courtyard)	N/A	N/A

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**Day 3 – February 3, 2012**

<b>TIME</b>	<b>BOARDROOM</b>	<b>BIOLAB</b>	<b>CLEANROOM</b>
10:00 AM – 11:00 AM	Vistec Electron Beam Lithography Systems Mike Butler (Vistec)	N/A	Veeco AFM Demo Session 2 & Oxford RIE Demo Session 1 (Class 10,000)
11:00 AM – 12:00 PM	Omniprobe Autoprobe & OmniGIS systems for FIB-SEM Julie Sheffield-Parker (Nanospec)	N/A	Veeco AFM Demo Session 2 & Oxford RIE Demo Session 1 (Class 10,000)
12:00 PM – 1:00 PM	LUNCH	N/A	N/A
1:00 PM – 2:00 PM	Current trends in UV/VIS/NIR Spectrophotometry David Haines (Agilent)	N/A	EVG Mask Aligner/Hot Embosser Workshop 2 (Class 100) & Veeco AFM Demo Session 3 (Class 10,000)
2:00 PM – 3:00 PM	Broad Beam Ion Milling Systems – Capabilities & Applications Dino Deligiannis (IntlVac)	Agilent UV/VIS/NIR Spectrophotometer Demo - TBC	Veeco AFM Demo Session 3 (Class 10,000)
3:00 PM – 3:30 PM	Program Close/Thanks		